



- (51) **International Patent Classification:**
G01N 21/88 (2006.01) *G01N 21/17* (2006.01)
- (21) **International Application Number:**
PCT/US2025/016332
- (22) **International Filing Date:**
18 February 2025 (18.02.2025)
- (25) **Filing Language:** English
- (26) **Publication Language:** English
- (30) **Priority Data:**
18/581,858 20 February 2024 (20.02.2024) US
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(81) **Designated States** (*unless otherwise indicated, for every kind of national protection available*): AE, AG, AL, AM, AO, AT, AU, AZ, BA, BB, BG, BH, BN, BR, BW, BY, BZ, CA, CH, CL, CN, CO, CR, CU, CV, CZ, DE, DJ, DK, DM, DO, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, GT, HN, HR, HU, ID, IL, IN, IQ, IR, IS, IT, JM, JO, JP, KE, KG, KH, KN, KP, KR, KW, KZ, LA, LC, LK, LR, LS, LU, LY, MA, MD, MG, MK, MN, MU, MW, MX, MY, MZ, NA, NG, NI, NO, NZ, OM, PA, PE, PG, PH, PL, PT, QA, RO, RS, RU, RW, SA, SC, SD, SE, SG, SK, SL, ST, SV, SY, TH, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UY, UZ, VC, VN, WS, ZA, ZM, ZW.

(84) **Designated States** (*unless otherwise indicated, for every kind of regional protection available*): ARIPO (BW, CV, GH, GM, KE, LR, LS, MW, MZ, NA, RW, SC, SD, SL, ST, SZ, TZ, UG, ZM, ZW), Eurasian (AM, AZ, BY, KG, KZ, RU, TJ, TM), European (AL, AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HR, HU, IE, IS, IT, LT, LU, LV, MC, ME, MK, MT, NL, NO, PL, PT, RO, RS, SE, SI, SK, SM, TR), OAPI (BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, KM, ML, MR, NE, SN, TD, TG).

Published:

— with international search report (Art. 21(3))

(54) **Title:** SAMPLE INSPECTION WITH MULTIPLE MEASUREMENT MODES

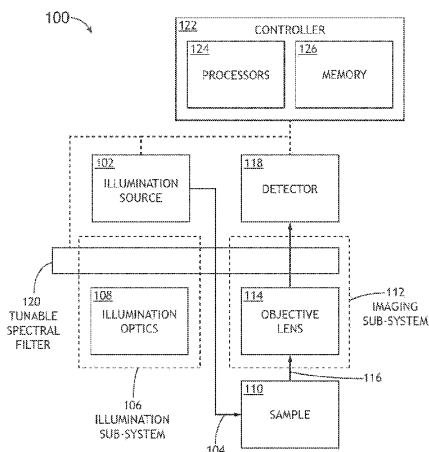


FIG. 1A

(57) **Abstract:** An inspection system may include an illumination source configured to generate an illumination beam with multiple wavelengths, an illumination sub-system including one or more illumination optics to direct the illumination beam to a sample at an off-axis angle, and an imaging sub-system. The system may include an objective lens to collect sample light, where the objective lens exhibits chromatic aberration within a spectrum of the illumination beam. The system may include one or more detectors to image the sample. A size of a point spread function (PSF) of the imaging sub-system relative to a pixel size of at least one of the one or more detectors may be adjustable. The system may include a tunable spectral filter with an adjustable linewidth configured to selectively adjust a spectrum of at least one of the illumination beam or the sample light.